



OPEN

Docket No.: WEN-0020
(PATENT)

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of:
Masanao Fujieda

Application No.: 10/626,527

Conf. No. 1114

Filed: July 25, 2003

Art Unit: 3739

For: METHOD AND APPARATUS FOR
OBTAINING IRRADIATION INTENSITY OF
A LASER BEAM, AND APPARATUS FOR
IRRADIATING THE LASER BEAM

Examiner: Not Yet Assigned

STATUS INQUIRY

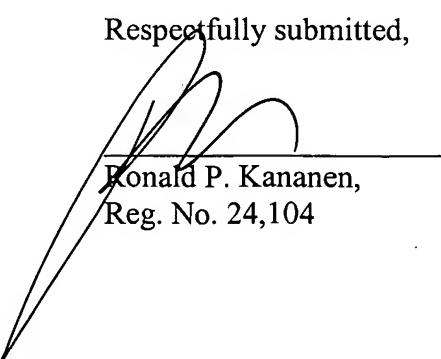
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Please inform the undersigned when the initial Action on the merits of the above-identified application may be expected. The application has now been pending 18 months without an action on the merits.

Date: February 2, 2005

Respectfully submitted,


Ronald P. Kananen,
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